

### **Carol Livermore**

### **Massachusetts Institute of Technology**

# \* With thanks to Steve Senturia, from whose lecture notes some of these materials are adapted.

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### Outline

### > Regroup

### > Beam bending

- Loading and supports
- Bending moments and shear forces
- Curvature and the beam equation
- Examples: cantilevers and doubly supported beams

### > A quick look at torsion and plates

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### **Recall: Isotropic Elasticity**

- > For a general case of loading, the constitutive relationships between stress and elastic strain are as follows
- > 6 equations, one for each normal stress and shear stress

### What we are considering today

- > Bending in the limit of small deflections
- > For axial loading, deflections are small until something bad happens
  - Nonlinearity, plastic deformation, cracking, buckling
  - Strains typically of order 0.1% to 1%
- > For bending, small deflections are typically less than the thickness of the element (i.e. beam, plate) in question

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### What we are NOT considering today

- > Basically, anything that makes today's theory not apply (not as well, or not at all)
- > Large deflections
  - Axial stretching becomes a noticeable effect
- > Residual stresses
  - Can increase or decrease the ease of bending

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### **Our trajectory**

> What are the loads and the supports?



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> What is the bending moment at point x along the beam?

> How much curvature does that bending moment create in the structure at x? (Now you have the beam equation.)

#### > Integrate to find deformed shape

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- > Three basic types of loads:
  - Point force (an old friend, with its own specific point of application)
  - Distributed loads (pressure)
  - Concentrated moment (what you get from a screwdriver, with a specific point of application)
  - The forces and moments work together to make internal bending moments – more on this shortly



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### **Types of supports**

### > Four basic boundary conditions:

- Fixed: can't translate at all, can't rotate
- Pinned: can't translate at all, but free to rotate (like a hinge)
- Pinned on rollers: can translate along the surface but not off the surface, free to rotate
- Free: unconstrained boundary condition



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### **Reaction Forces and Moments**

- > Equilibrium requires that the total force on an object be zero and that the total moment about any axis be zero
- > This gives rise to reaction forces and moments
- > "Can't translate" means support can have reaction forces
- > "Can't rotate" means support can have reaction moments

Total moment about support :

$$M_T = M_R - FL$$

Moment must be zero in equilibrium :

$$M_R = FL$$

Net force must be zero in equilibrium :

$$F_R = F$$

Image by MIT OpenCourseWare. Adapted from Figure 9.7 in: Senturia, Stephen D. *Microsystem Design*. Boston, MA: Kluwer Academic Publishers, 2001, p. 209. ISBN: 9780792372462.

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Point Load

### **Internal forces and moments**

- > Each segment of beam must also be in equilibrium
- > This leads to internal shear forces V(x) and bending moments M(x)
  For this case,



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### **Some conventions**



### **Combining all loads**

> A differential beam element, subjected to point loads, distributed loads and moments in equilibrium, must obey governing differential equations



Image by MIT OpenCourseWare.

Adapted from Figure 9.8 in: Senturia, Stephen D. *Microsystem Design*. Boston, MA: Kluwer Academic Publishers, 2001, p. 210. ISBN: 9780792372462.

$$F_T = qdx + (V + dV) - V \qquad M_T = (M + dM) - M - (V + dV)dx - \frac{qdx}{2}dx$$
$$\Rightarrow \frac{dV}{dx} = -q \qquad \Rightarrow \frac{dM}{dx} = V$$

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### **Pure bending**

- > Important concept: THE NEUTRAL AXIS
- > Axial stress varies with transverse position relative to the neutral axis



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### Locating the neutral axis

In pure bending, locate the neutral axis by imposing equilibrium of axial forces

$$N = \int_{A} \sigma(z) dA = 0$$
  
One material, rectangular beam  
$$- \int_{thickness} \frac{E(z)W(z)z}{\rho} dz = 0$$
  
$$- \int_{thickness} \frac{E(z)W(z)z}{\rho} dz = 0$$

- > The neutral axis is in the middle for a one material beam of symmetric cross-section.
- > Composite beams: if the beam just has a very thin film on it, can approximate neutral axis unchanged
- > Composite beams: with films of comparable thickness, change in E biases the location of the neutral axis

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### **Curvature in pure bending**

#### Curvature is related to the internal bending moment M.

For a one - material beam,

E<sub>e</sub>

Internal Moment :

$$M = \int_{A} z \sigma_{x} dA$$

$$M = -\frac{I}{\rho} \int_{A} z^{2} dA$$
Moment of inertia I:  

$$\sigma_{x} = -\frac{zE}{\rho}$$

$$M = -\frac{1}{\rho} \int_{A} E(z) z^{2} dA$$

$$M = -\frac{EI}{\rho}$$

In pure bending, the internal moment *M* equals the externally applied moment  $M_0$ . Then  $\frac{1}{\rho} = -\frac{M_0}{EI}$  for one material; for two

or more materials, calculate an effective El.

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For a uniform rectangular beam,

$$I = \int_{-H/2}^{H/2} Wz^2 dz = \frac{1}{12} WH^3$$
$$M = -\left(\frac{1}{12}WH^3\right)\frac{E}{\rho}$$

### **Differential equation of beam bending**

> Relation between curvature and the applied load



Image by MIT OpenCourseWare.

Adapted from Figure 9.11 in: Senturia, Stephen D. *Microsystem Design*. Boston, MA: Kluwer Academic Publishers, 2001, pp. 214. ISBN: 9780792372462.



 $\frac{d^2 w}{dx^2} = -\frac{M}{EI}$ and, by successive differentiation  $\frac{d^3 w}{dx^3} = -\frac{V}{EI}$  $\frac{d^4 w}{dx^4} = \frac{q}{EI}$ 

For large - angle bending

 $\frac{1}{\rho} = \frac{w''}{\left[1 + (w')^2\right]^{3/2}}$ 

## Large-angle bending is rare in MEMS structures

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### **Anticlastic curvature**

If a beam is bent, then the Poisson effect causes opposite bending in the transverse direction



which creates a y - directed internal moment

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Adapted from Figure 9.12 in: Senturia, Stephen D. *Microsystem Design*. Boston, MA: Kluwer Academic Publishers, 2001, pp. 219. ISBN: 9780792372462.

### **Example: Cantilever with point load**



$$\frac{d^2w}{dx^2} = \frac{F}{EI}(L-x)$$



$$w = -\frac{F}{6EI}x^3 + \frac{FL}{2EI}x^2 + Ax + B$$

BC: 
$$w(0) = 0, \left. \frac{dw}{dx} \right|_{x=0} = 0$$

$$A = B = 0$$

$$w = \frac{FL}{2EI} x^2 \left( 1 - \frac{x}{3L} \right)$$

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### **Spring Constant for Cantilever**

> Since force is applied at tip, if we find maximum tip displacement, the ratio of displacement to force is the spring constant.

$$w_{\max} = \left(\frac{L^3}{3EI}\right)F$$

$$\Downarrow$$

$$k_{cantilever} = \frac{3EI}{L^3} = \frac{EWH^3}{4L^3}$$

#### For the same dimensions as the uniaxially loaded beam,

$$k_{cantilever} = 0.2 \text{ N/m}$$

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### **Stress in the Bent Cantilever**

> To find bending stress, we find the radius of curvature, then use the pure-bending case to find stress

Radius of curvature : 
$$\frac{1}{\rho} = \frac{d^2 w}{dx^2} = \frac{F}{EI}(L-x)$$
  
Maximum value is at support  $(x = 0)$   
 $\frac{1}{\rho}\Big|_{max} = \frac{FL}{EI}$   
Maximum axial strain is at surface  $(z = H/2)$   
 $\varepsilon_{max} = \frac{LH}{2EI}F = \frac{6L}{H^2WE}F$   
 $\sigma_{max} = \frac{6L}{H^2W}F$ 

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### **Tabulated solutions**

- > Solutions to simple situations available in introductory mechanics books
  - Point loads, distributed loads, applied moments
  - Handout from Crandall, Dahl, and Lardner, An Introduction to the Mechanics of Solids, 1999, p. 531.
- > Linearity: you can superpose the solutions
- > Can save a bit of time
- > Solutions use nomenclature of singularity functions

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### **Singularity functions**

$$\langle x-a \rangle^n = 0$$
 if  $x-a < 0$   
 $\langle x-a \rangle^n = (x-a)^n$  if  $x-a > 0$   
 $\langle x-a \rangle^{-1}$  = what is variably called an impulse or a delta function

Integrate as if it were just functions of (x-a); evaluate at the end.

Value: a single expression describes what's going on in different regions of the beam



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### **Overconstraint**

> A cantilever's single support provides the necessary support reactions and no more



> A fixed-fixed beam has an additional support, so it is overconstrained



- Static indeterminacy: must consider deformations and reactions to determine state of the structure
- > Many MEMS structures are statically indeterminate: flexures, optical MEMS, switches,...
- > What this means for us
  - Failure modes and important operational effects: stress stiffening, buckling
  - Your choice of how to calculate deflections

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### Example: center-loaded fixed-fixed beam

- > Option 1: (general)
  - Start with beam equation in terms of q
  - Express load as a delta function
  - Integrate four times
  - Four B.C. give four constants
- > Option 2: (not general)
  - Invoke symmetry
- > Option 3: (general)
  - Pretend beam is a cantilever with as yet unknown moment and force applied at end such that w(L) = slope(L) = 0
  - Using superposition, solve for deflection and slope everywhere
  - Impose B.C. to determine moment and force at end
  - Plug newly-determined moment and force into solution, and you're done





#### Integration using singularity functions



$$q = F \left\langle x - L/2 \right\rangle^{-1}$$

$$\frac{d^{4}w}{dx^{4}} = \frac{q}{EI} = \frac{F}{EI} \langle x - L/2 \rangle^{-1}$$
Use boost on state of the second second

Use boundary conditions to find constants: no displacement at supports, slope = 0 at supports

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### **Comparing spring constants**

> Center-loaded fixed-fixed beam (same dimensions as previous)



> Tip-loaded cantilever beam, same dimensions



> Uniaxially loaded beam, same dimensions



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### Torsion

#### The treatment of torsion mirrors that of bending.

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Figures 48 and 50 in: Hornbeck, Larry J. "From Cathode Rays to Digital Micromirrors: A History of Electronic Projection Display Technology." *Texas Instruments Technical Journal* 15, no. 3 (July-September 1998): 7-46.

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Figure 51 on p. 39 in: Hornbeck, Larry J. "From Cathode Rays to Digital Micromirrors: A History of Electronic Projection Display Technology." *Texas Instruments Technical Journal* 15, no. 3 (July-September 1998): 7-46.

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### **Bending of plates**

- > A plate is a beam that is so wide that the transverse strains are inhibited, both the Poisson contraction and its associated anticlastic curvature
- > This leads to additional stiffness when trying to bend a plate

$$\varepsilon_x = \frac{\sigma_x - \nu \sigma_y}{E}$$

But  $\varepsilon_y$  is constrained to be zero

$$\Rightarrow 0 = \varepsilon_{y} = \frac{\sigma_{y} - v\sigma_{x}}{E}$$

$$\Downarrow$$

$$\sigma_{x} = \left(\frac{E}{1 - v^{2}}\right)\varepsilon_{x}$$

Plate Modulus

### Plate in pure bending

- > Analogous to beam bending, with the limit on transverse strains
- > Two radii of curvature along principal axes

> Str

$$\sigma_{x} = -\frac{Ez}{(1-v^{2})} \left( \frac{1}{\rho_{x}} + \frac{v}{\rho_{y}} \right)$$
$$\sigma_{y} = -\frac{Ez}{(1-v^{2})} \left( \frac{1}{\rho_{y}} + \frac{v}{\rho_{x}} \right)$$

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### Plate in pure bending

- > Relate moment per unit width of plate to curvature
- > Treat x and y equivalently



#### > Note that stiffness comes from flexural rigidity as for a beam

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### Plate in pure bending

> Recall that M is two derivatives away from a distributed load, and that

$$\frac{1}{\rho_x} = \frac{\partial^2 w}{\partial x^2} \qquad \qquad \frac{1}{\rho_y} = \frac{\partial^2 w}{\partial y^2}$$

> This leads to the equation for small amplitude bending of a plate

$$D\left(\frac{\partial^4 w}{\partial x^4} + 2\frac{\partial^4 w}{\partial x^2 \partial y^2} + \frac{\partial^4 w}{\partial y^4}\right) = P(x, y)$$
  
distributed load

> Often solve with polynomial solutions (simple cases) or eigenfunction expansions

- > We can handle small deflections of beams and plates
- > Physics intervenes for large deflections and residual stress, and our solutions are no longer correct
- > Now what do we do?
  - Residual stress: include it as an effective load
  - Large deflections: use Energy Methods

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